

10/520099

DT12 Rec'd PCT/PTO 0 4 JAN 2005

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Ryoji HOSHI et al.

Application No.: New U.S. National Stage of PCT/JP03/08671

Filed: January 4, 2005

Docket No.: 122336

For: A SILICON WAFER FOR EPITAXIAL GROWTH, AN EPITAXIAL WAFER, AND  
A METHOD FOR PRODUCING IT

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Please consider the following:

**Amendments to the Claims** as reflected in the listing of claims;

**Remarks.**